

SPIRAL™

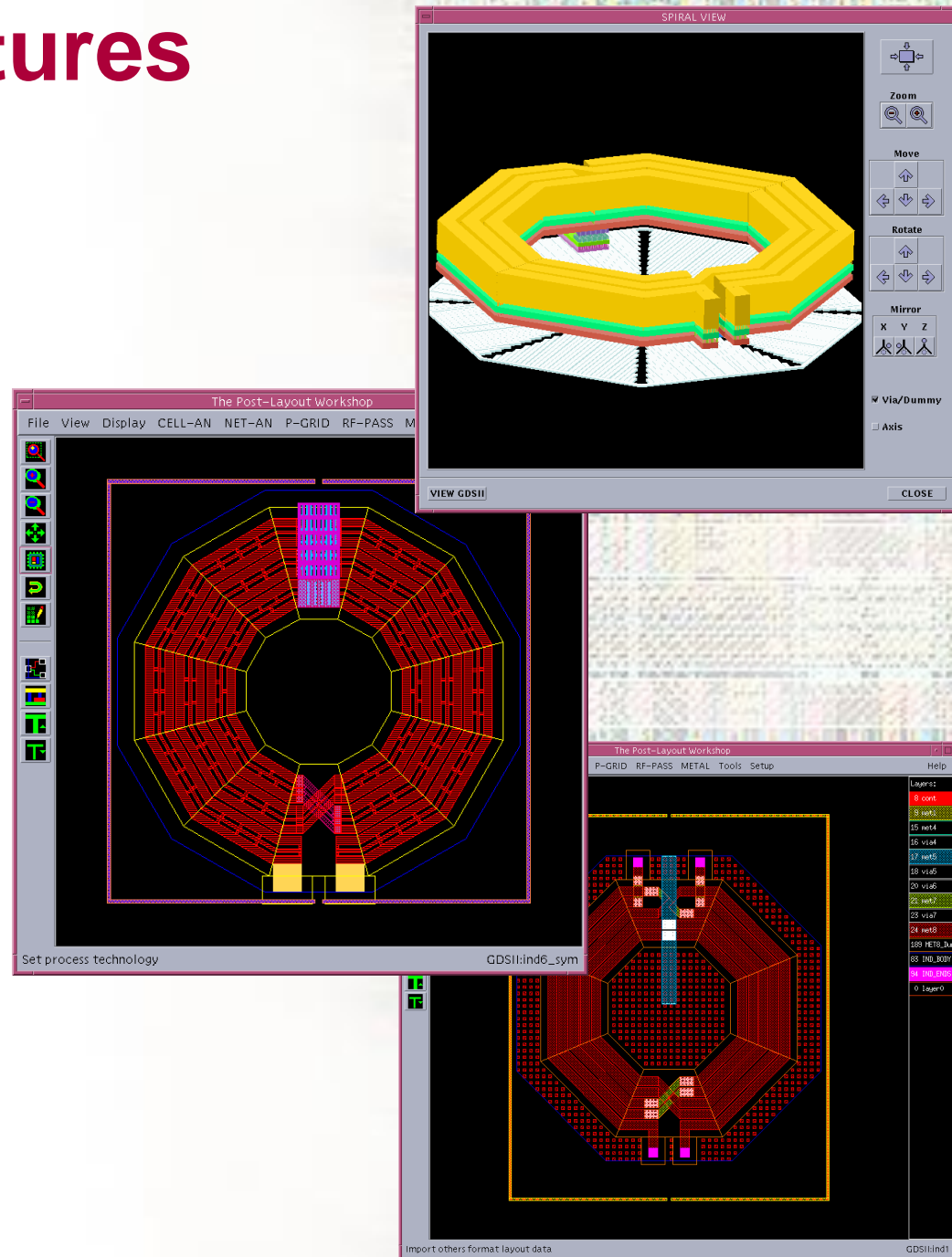
3D Spiral Inductance Synthesis and Design Tool

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www.oea.com



SPIRAL Features

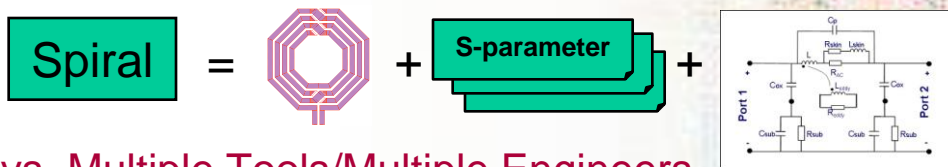
- Fully Automatic Synthesis of Spiral Inductors, Differential Inductors, Baluns, and Transformers
 - Full Physical DRC Clean Layout in GDSII or DF2 Format
 - Full Spice RCLK Output
 - Compact Model to Fit Narrow or Wide-Band Applications
 - S-, Y-, and Z-Parameter Models
 - Monte Carlo and EM Analysis
- Very High Accuracy & FAST
 - Matches Measured Silicon
 - Patterned Ground Shield Support
 - Substrate, Skin & Proximity Effect
- Ready for 90nm & 65nm Design
 - Dummy Metal Fill (for CMP)
 - Slotting to User DRC Rules
- Extremely Easy to Use
 - Targeted for RF Designer
 - Automatic Optimization for best Q at frequency and size
 - Automatic Design Space Exploration
- Multiple Use Models
 - Standalone Batch and Interactive Operation
 - Fully Integrated with Cadence



Spiral Value Proposition

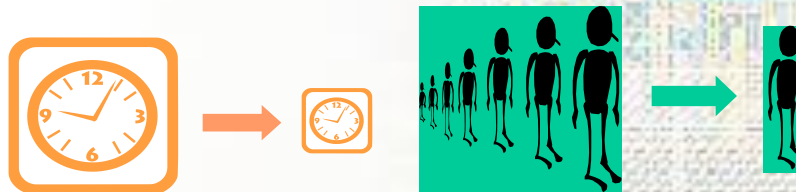
Significant Time/Effort-to-Model Reduction

- Single Tool produces layout, S-, Y-, Z- Parameters, and Compact Spice Model



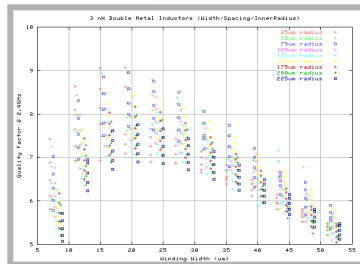
- Single Tool/Single Engineer vs. Multiple Tools/Multiple Engineers

Very Fast Runtime - Minutes vs. Hours

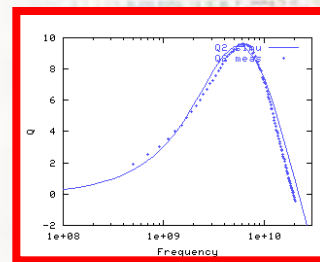


- Thorough Design Space Exploration

- Ensures Optimum Device is Found

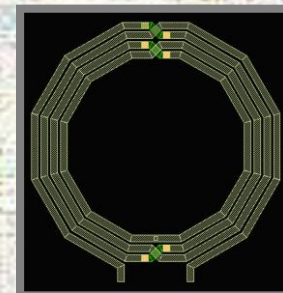


- High Accuracy – Simulations Match Measurements

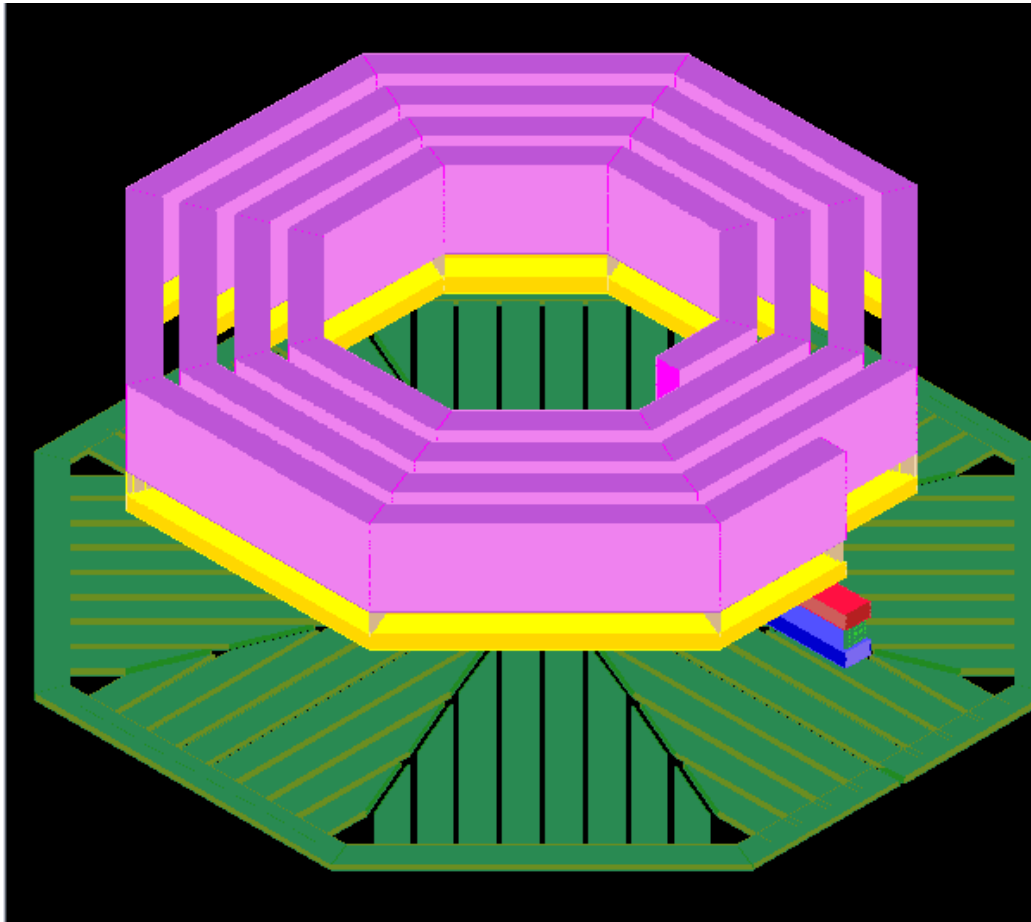


- Make Alternative Spiral Types Readily Available

- Provides significant performance and die size benefits



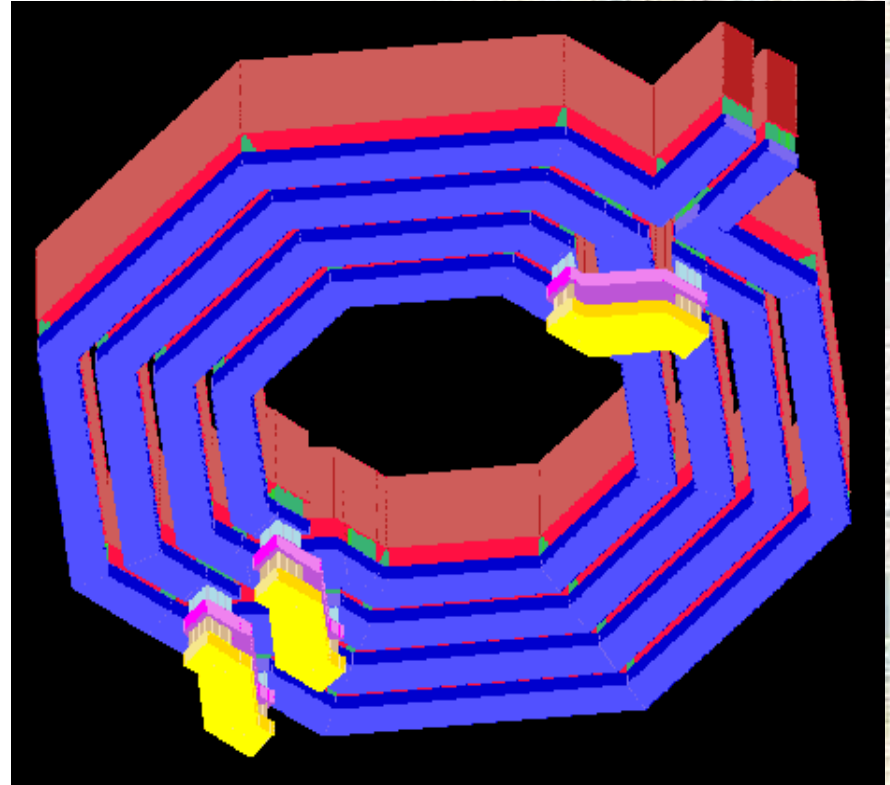
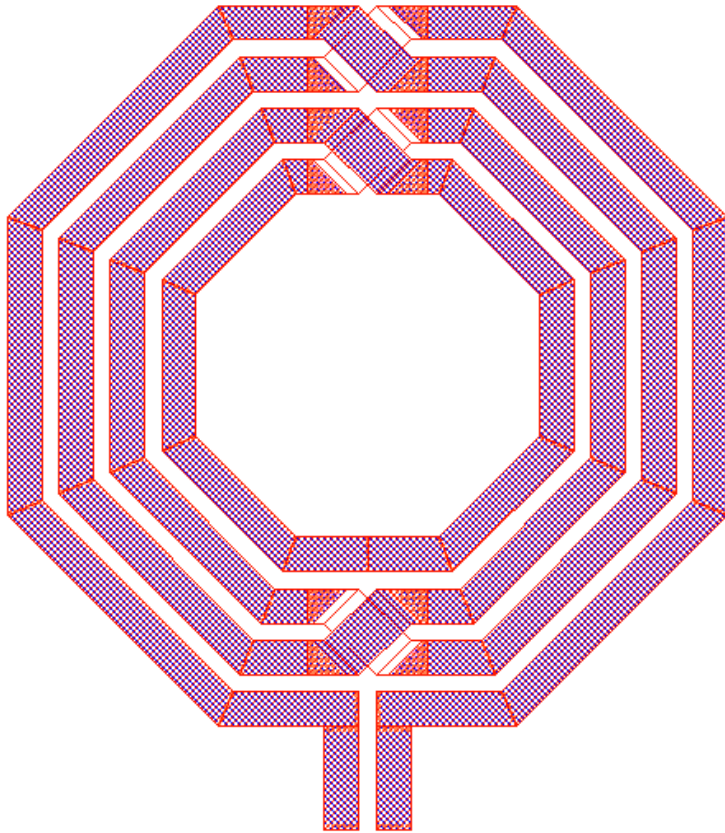
Standard Two Port Inductors



**Optimization Requires
Choosing:**

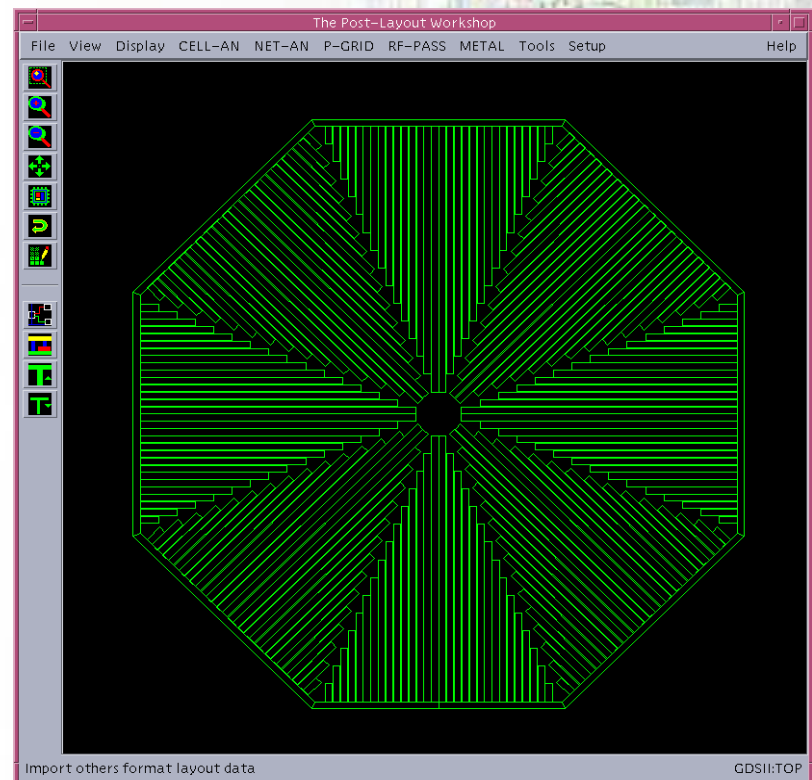
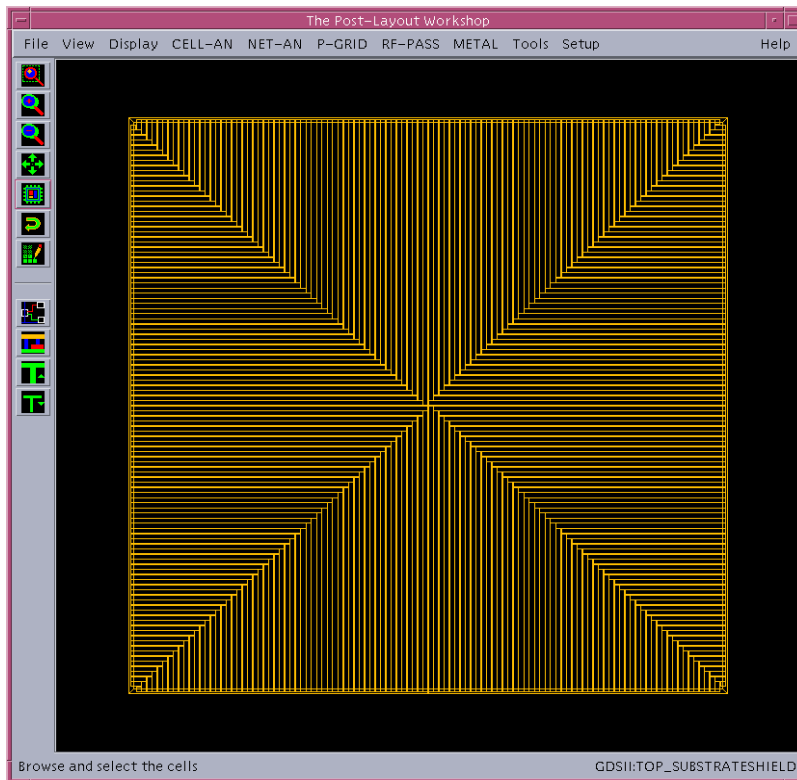
- Metal layer(s)
- Radius
- Winding Width
- Bridge Width
- Spacing
- Etc...

Symmetric 3-Port Differential Inductors

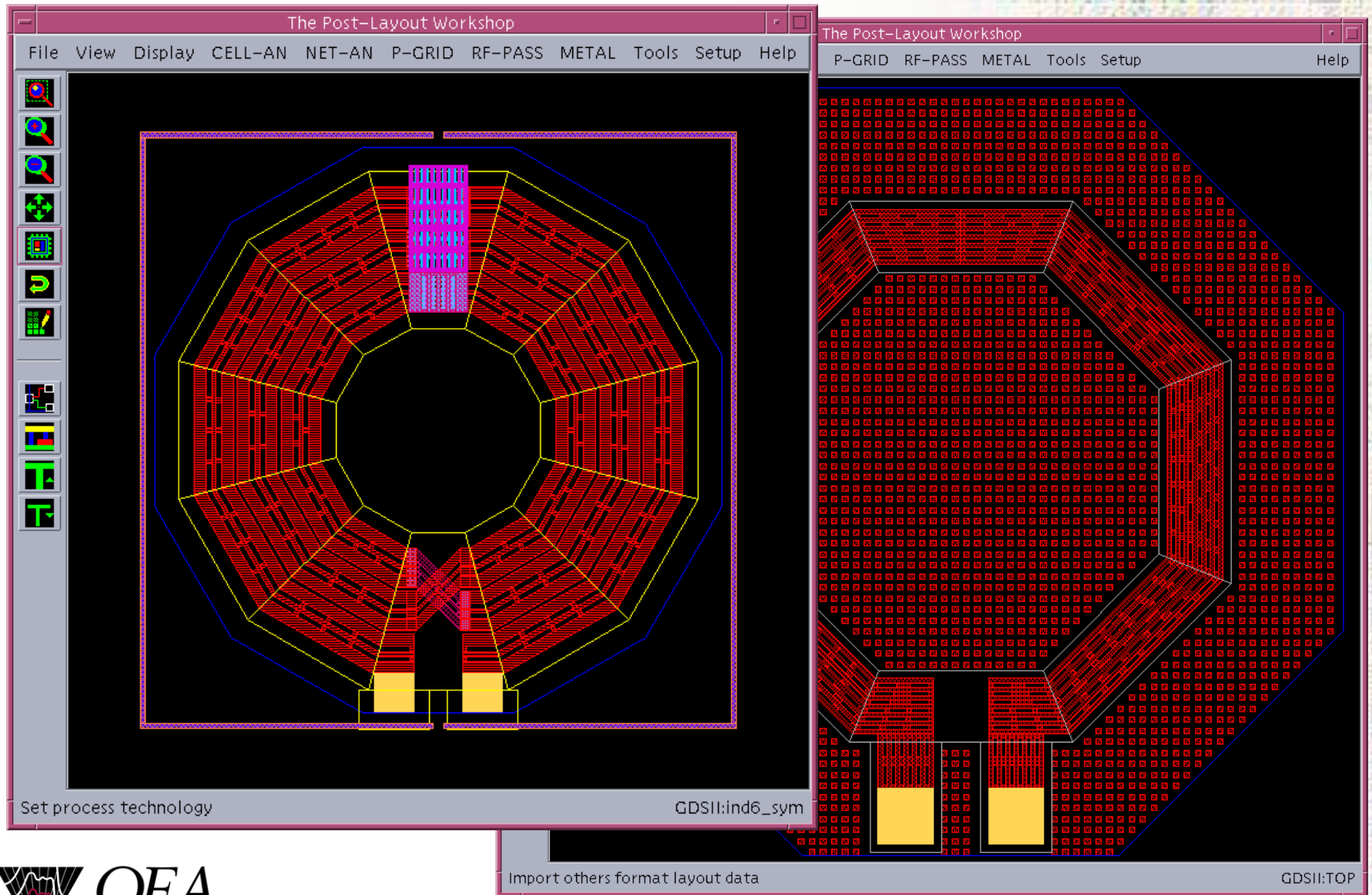


- **Symmetric Center Tapped Inductors instead of 2 ‘uncoupled’ inductors:**
 - Easily defined center tap
 - Reduced chip area
 - Higher Q (reduced substrate losses)
 - No need to model parasitic coupling

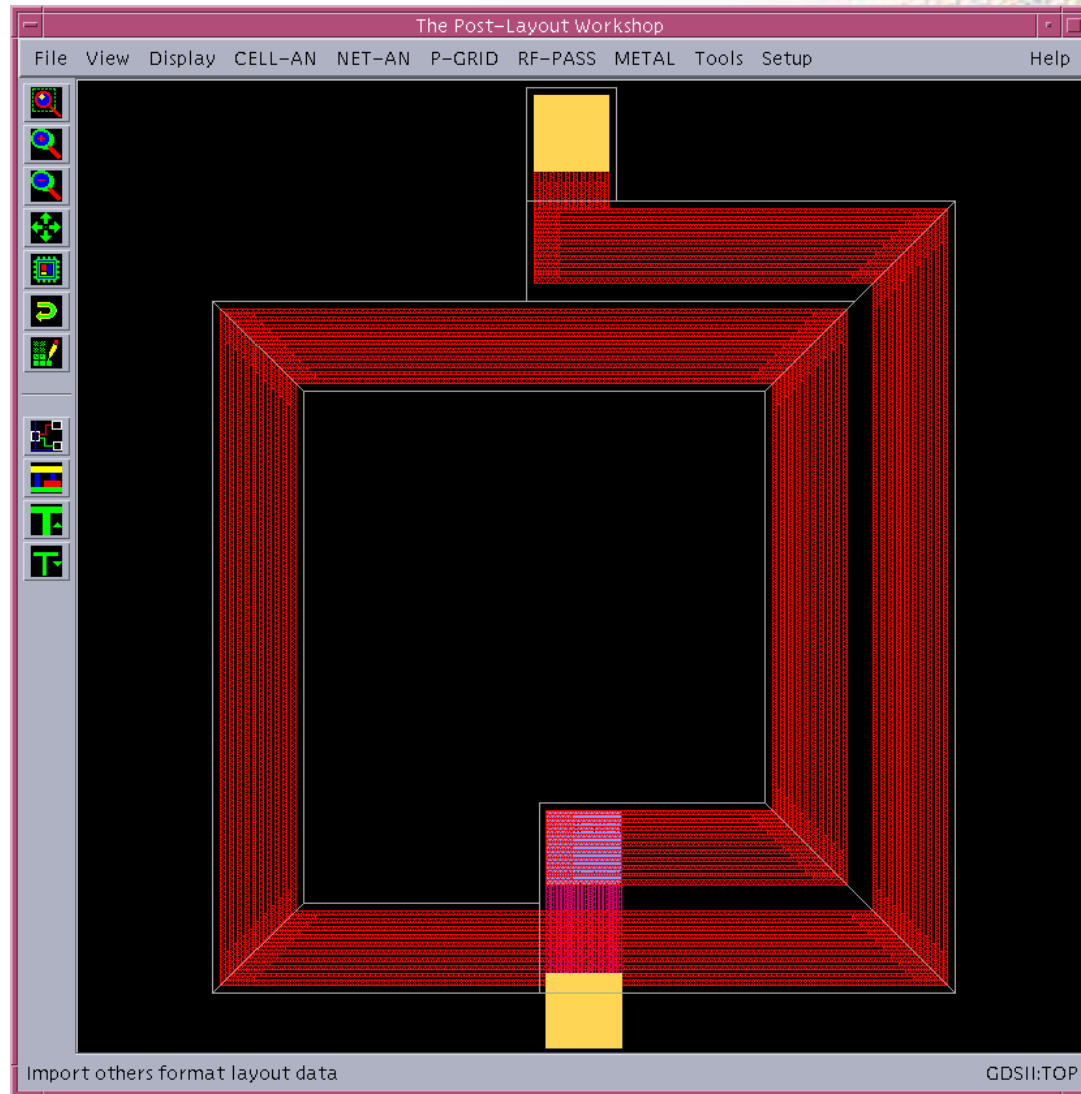
Patterned Ground Shields



Slotted Spiral Inductors With or Without Dummy Metal Fill

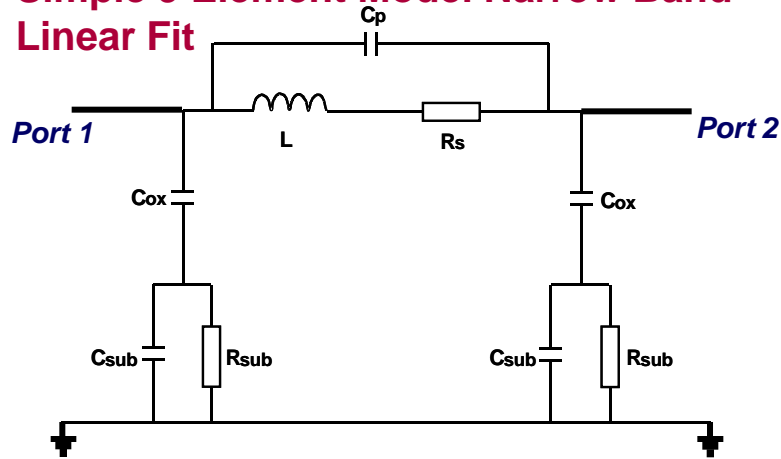


Striped Spiral Inductor with Connections at Corners

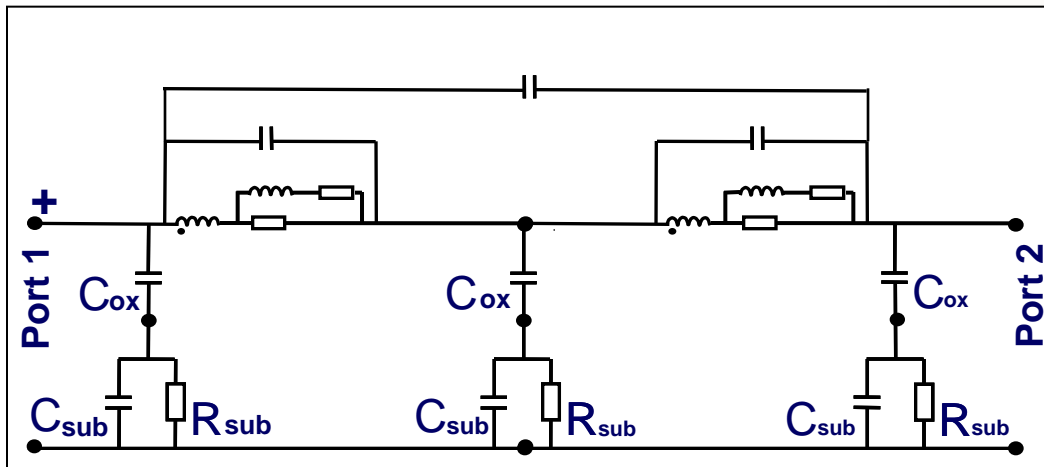
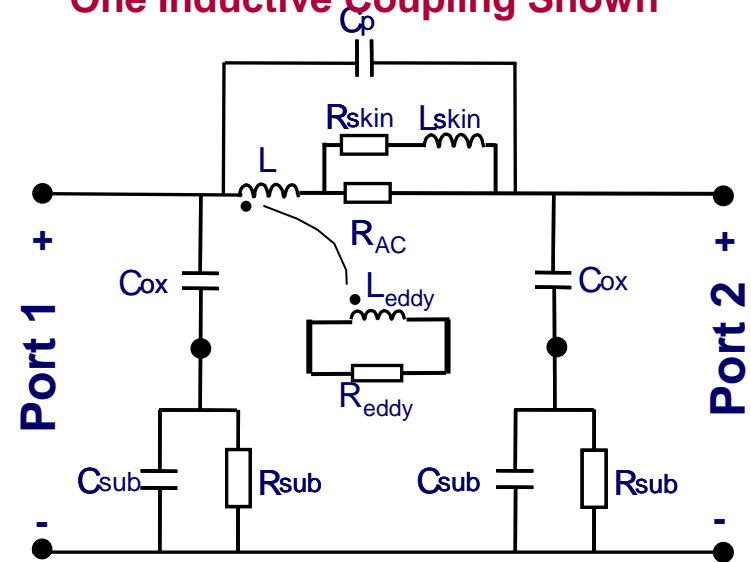


Compact Model Fitting

Simple 9 Element Model Narrow Band Linear Fit

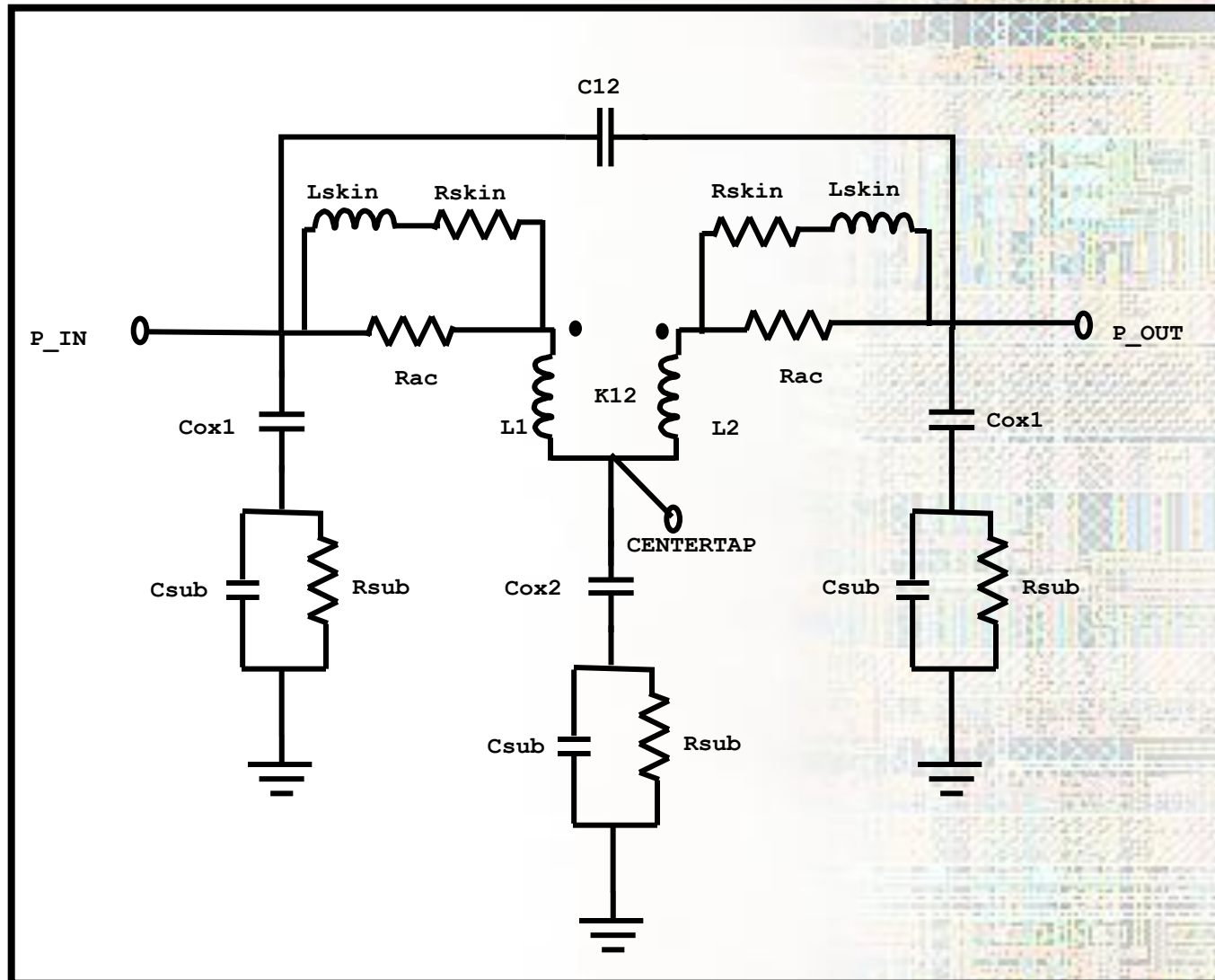


Enhanced 13 Element Model Plus One Inductive Coupling Shown

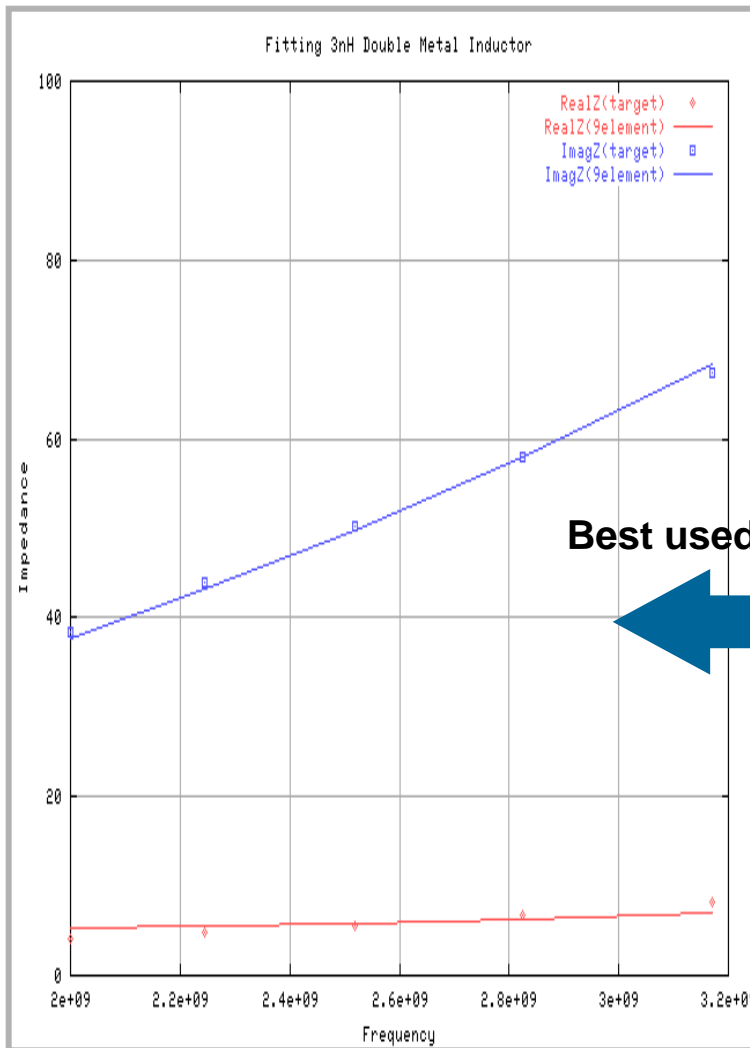


**Berkeley / IBM 2Π
Model (Mutual
Inductances not
Shown) Often Fits
past Resonance**

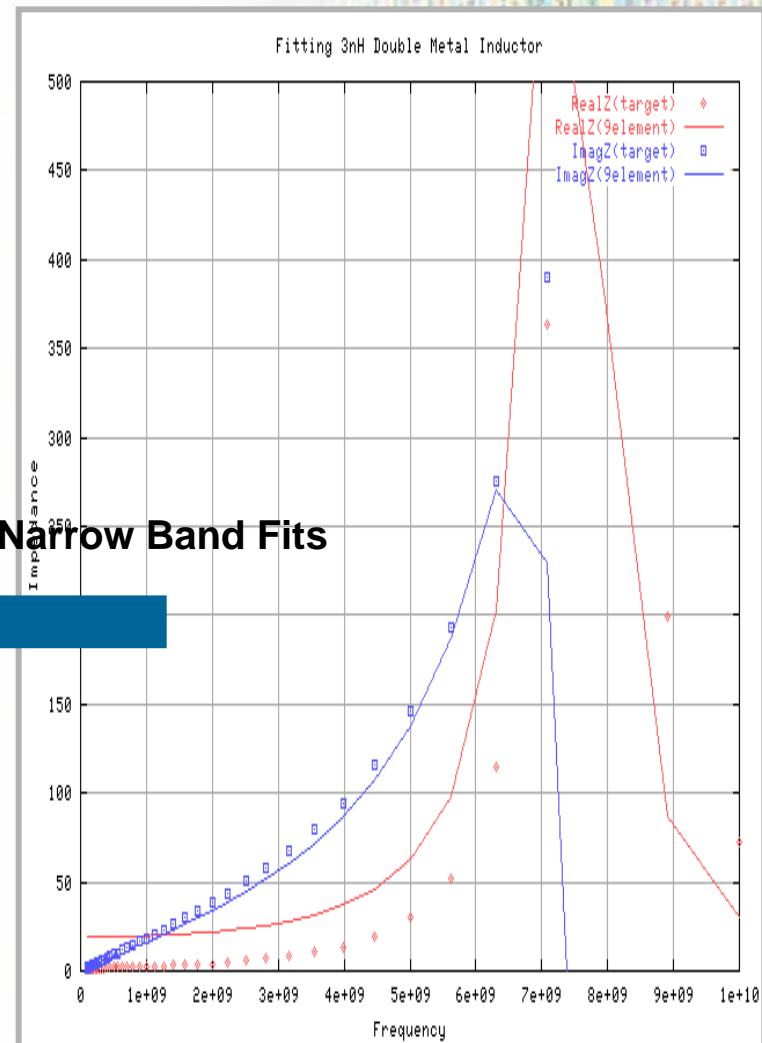
Symmetric Inductor Lumped Model



9 Element Model Fit



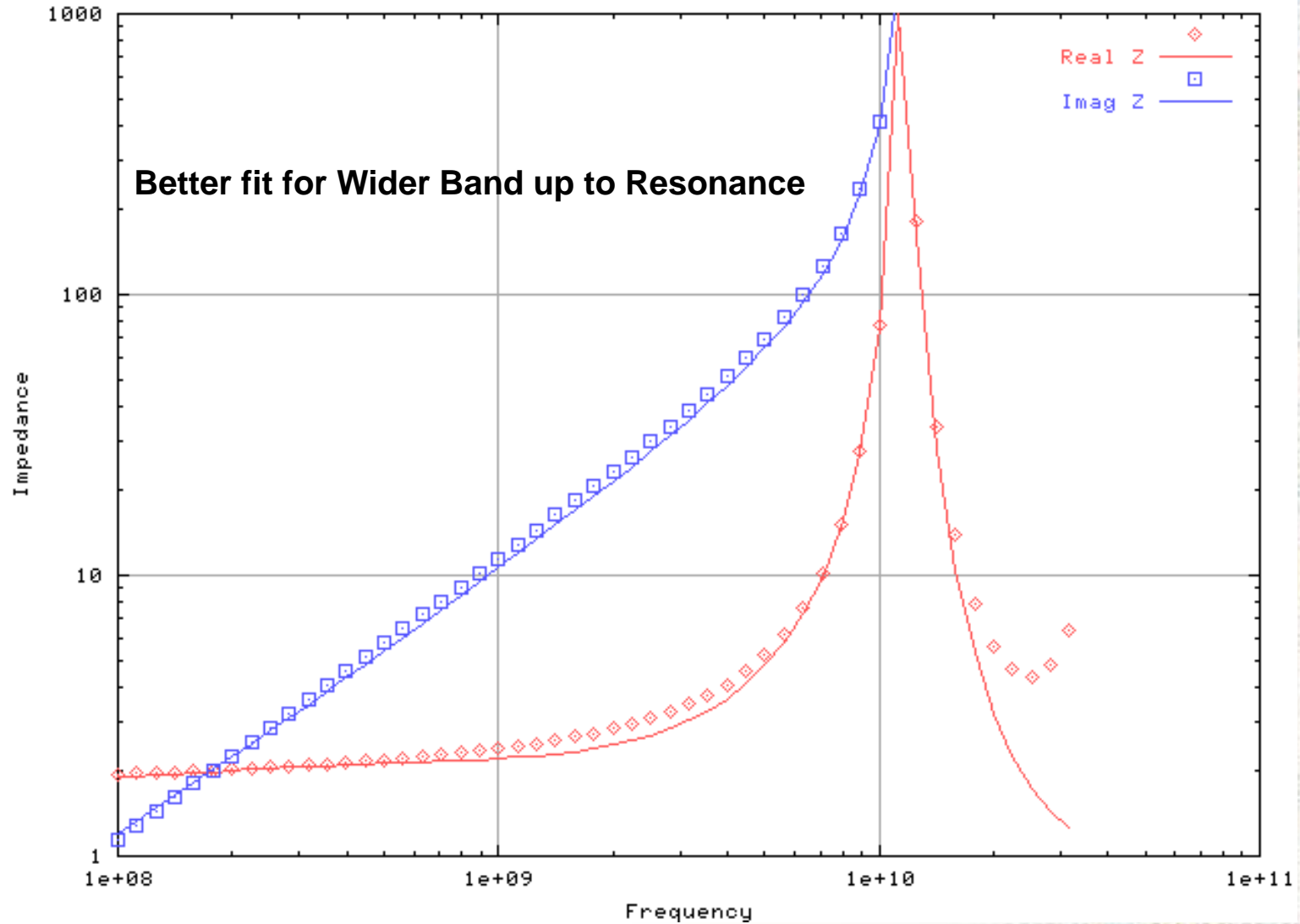
Best used for Narrow Band Fits



Narrow Band Fit

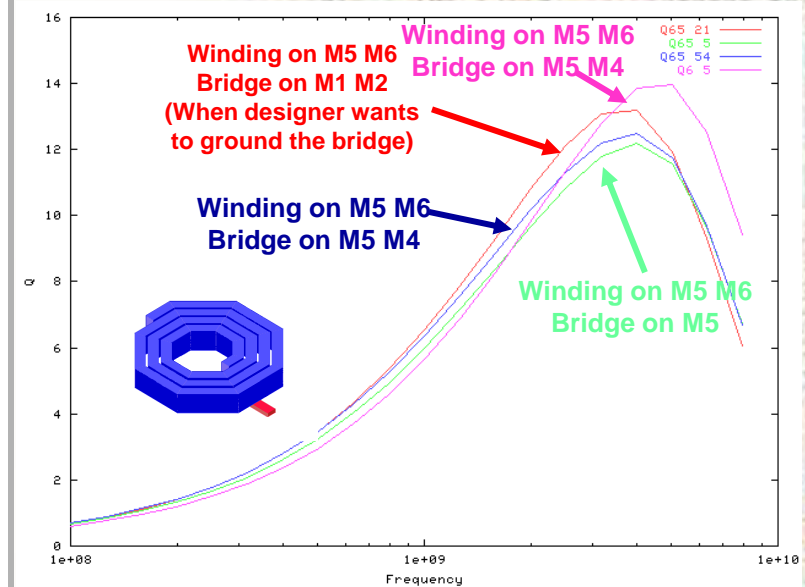
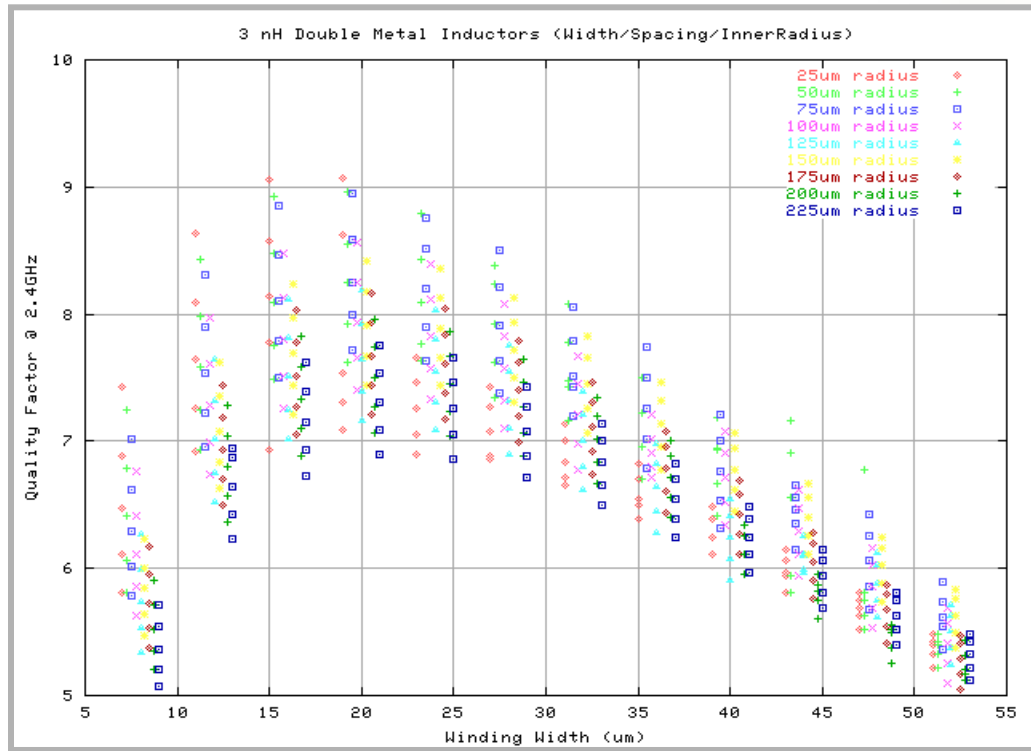
Wide Band Misfit

Broadband 13 Element Model Fit



Spiral Value Proposition

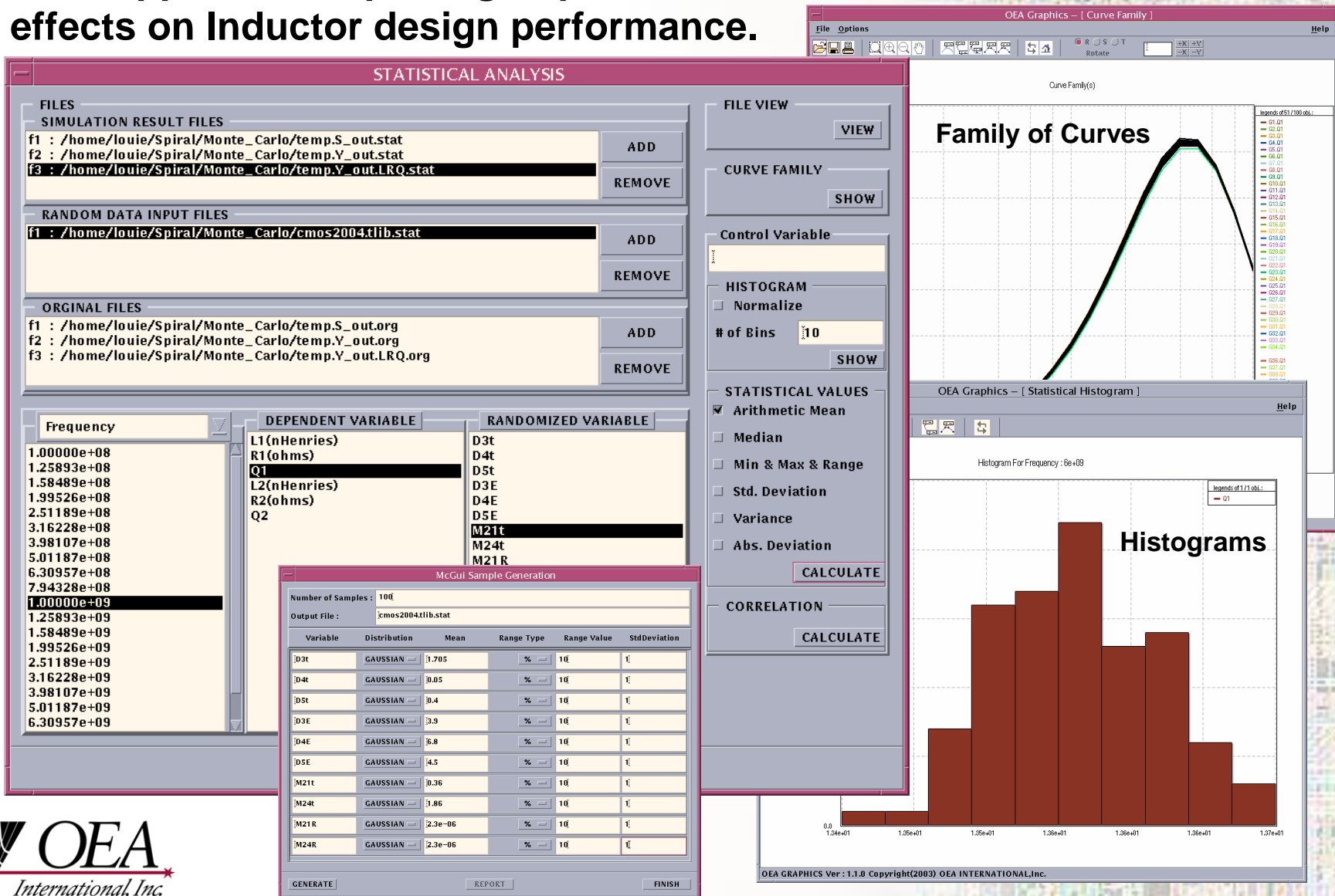
Design Space Exploration & Optimum Device Synthesis



- Thousands of Solutions Synthesized
- Performance/Area Tradeoffs Easily Analyzed
- Guides Designer to Correct Implementation to Optimize

Spiral Monte Carlo Analysis

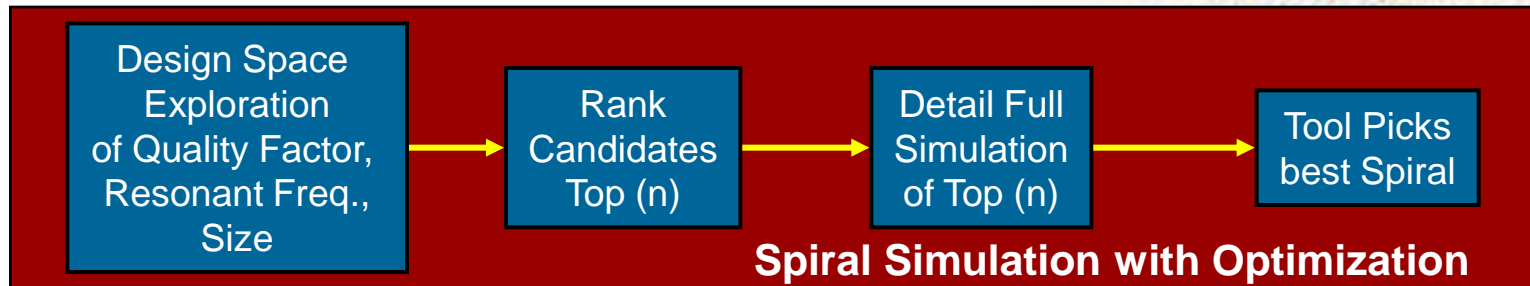
Full support and reporting of process variation effects on Inductor design performance.



Spiral Value Proposition

Improved Design Performance/Quality

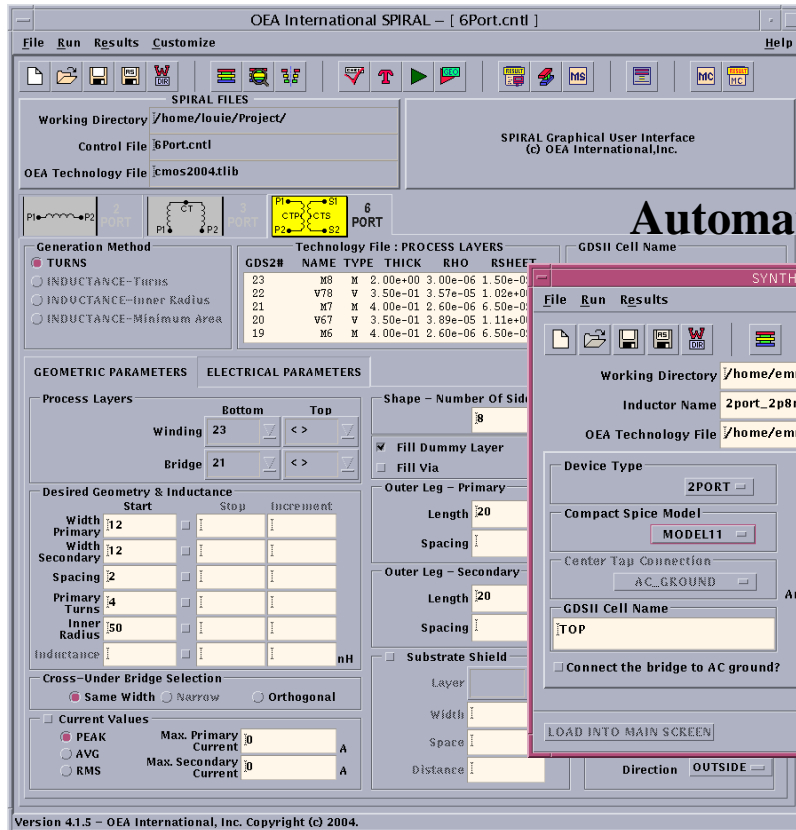
- **Ease of Use Enables Deployment to Designer's Desktop**
 - Tight Integration with Cadence Composer and Artist
 - No EM Knowledge Required



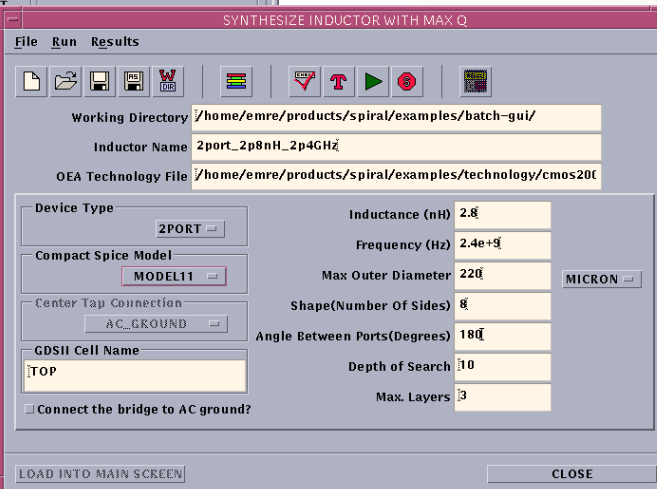
- **Design Specific Component Optimization**
 - By Frequency, Area, Port Locations
 - Better Yield: Models Include Process Variations

Spiral's Ease of Use Enables Widespread Deployment

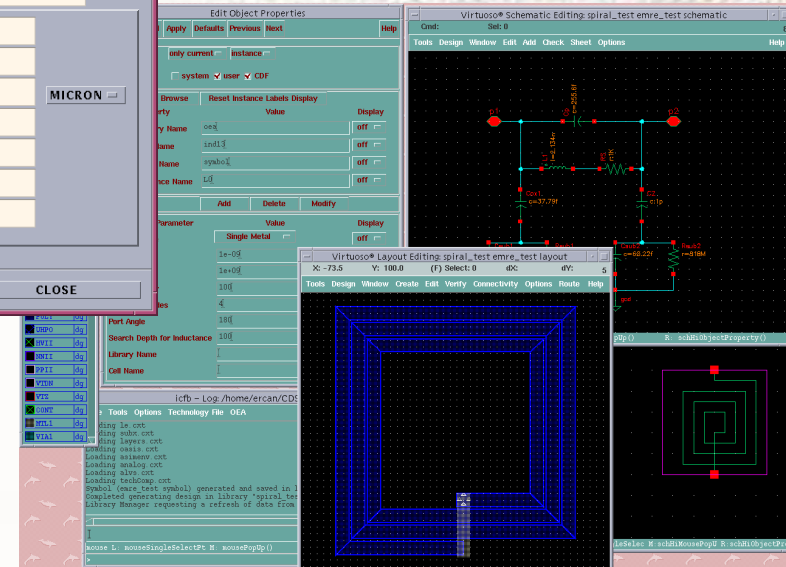
User Defined Geometry Mode



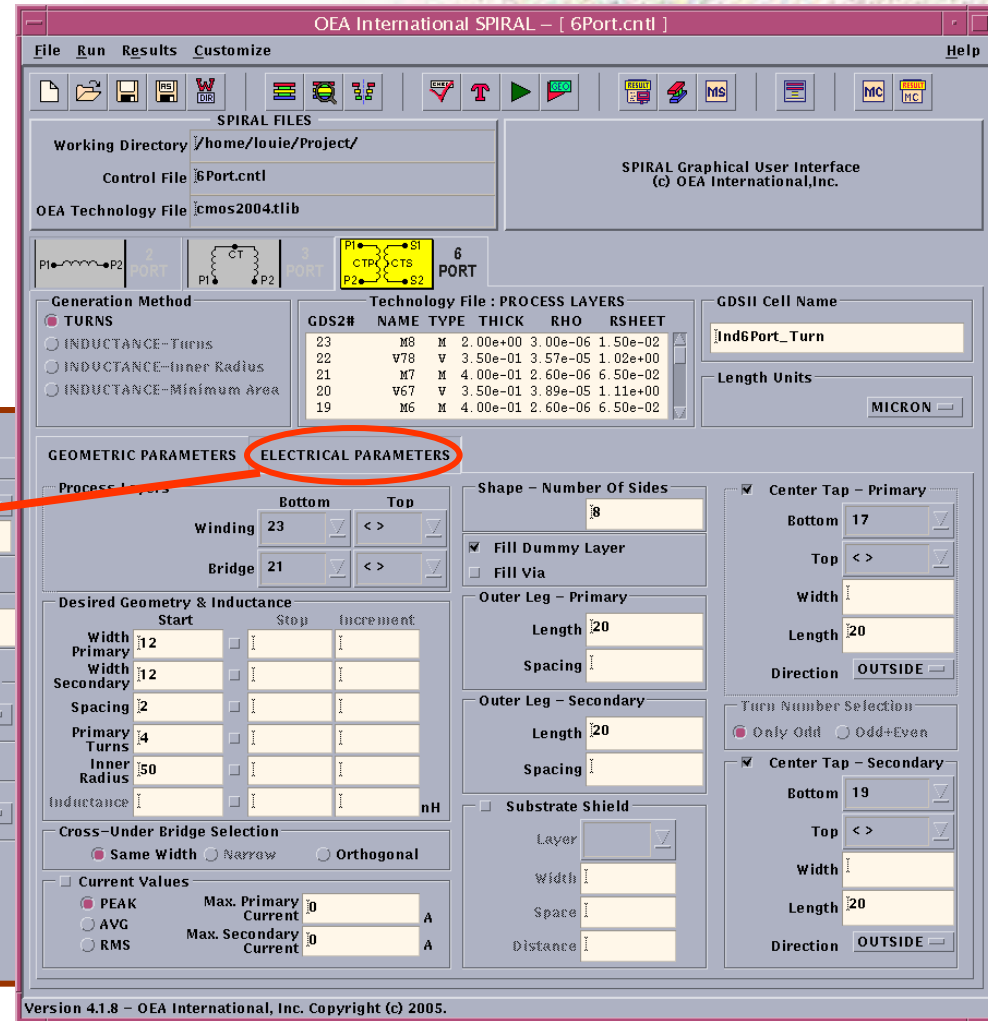
Automated Synthesis Mode



Cadence Integration



Full Range of Parameter Definitions for Customizing Inductor



Process Technology File Defines Physical Properties

TECHNOLOGY CMOS99

UNIT MICRONS

Units of microns apply to all length dimensions below

METAL

#Order	Layer	no	Name	Type	Z_min	Thickness	Resistivity	J(PEAK	AVE	RMS)	EdgeBias
1	1		POLY	P	0.350	0.200	1.56E-04	1.00E-03	0.00E+00	0.00E+00	0.00E+00
2	2		CT	C	1	3	2.90E-04	1.00E-03	0.00E+00	0.00E+00	0.00E+00
3	3		M1	M	1.050	0.530	4.13E-06	1.00E-03	0.00E+00	0.00E+00	0.00E+00
4	4		V1	V	3	5	1.02E-04	1.00E-03	0.00E+00	0.00E+00	0.00E+00
5	5		M2	M	2.380	0.530	4.13E-06	1.00E-03	0.00E+00	0.00E+00	0.00E+00
6	6		V2	V	5	7	1.02E-04	1.00E-03	0.00E+00	0.00E+00	0.00E+00
7	7		M3	M	3.710	0.530	4.13E-06	1.00E-03	0.00E+00	0.00E+00	0.00E+00
8	10		V3	V	7	9	1.02E-04	1.00E-03	0.00E+00	0.00E+00	0.00E+00
9	45		M4	M	5.040	0.530	4.13E-06	1.00E-03	0.00E+00	0.00E+00	0.00E+00
10	8		V4	V	9	11	1.02E-04	1.00E-03	0.00E+00	0.00E+00	0.00E+00
11	50		M5	M	6.370	0.530	4.13E-06	1.00E-03	0.00E+00	0.00E+00	0.00E+00
12	9		V5	V	11	13	1.26E-04	1.00E-03	0.00E+00	0.00E+00	0.00E+00
13	51		M6	M	7.700	3.000	3.56E-06	1.00E-03	0.00E+00	0.00E+00	0.00E+00

ENDMETAL

DIELECTRIC

#Order	Type	Thickness	Epsilon(z	x	y)	
1	p	0.350	3.90E+00	3.90E+00	3.90E+00	# Si usually starts with a field oxide
2	p	0.700	4.00E+00	4.00E+00	4.00E+00	#
3	p	6.650	3.80E+00	3.80E+00	3.80E+00	#
4	p	4.000	4.20E+00	4.20E+00	4.20E+00	#
5	p	0.700	7.90E+00	7.90E+00	7.90E+00	# Passivation layer
6	p	10.000	1.00E+00	1.00E+00	1.00E+00	# Air

ENDDIELECTRIC

SUBSTRATE

#Order	Name	DopingType	Thickness	Resistivity	Epsilon(z	x	y)
-1	epi	p	2.0	0.1	11.9	11.9	11.9
-2	bulk	p	600.0	10.0	11.9	11.9	11.9
-3	metal	p	3.0	3.0e-6	1.0	1.0	1.0

ENDSUBSTRATE

DRCRULES

enclosure	51	9	0.5	# Layer 51 (M6) encloses layer 9 (V5) by 0.5 um
enclosure	50	9	0.1	# Layer 50 (M5) encloses layer 9 (V5) by 0.1 um
viasize	9	0.7		# Layer 9 (V5) size is 0.7 um
minspace	9	0.7		# Layer 9 (V5) spacing is 0.7 um between vias
minwidth	51	3.0		# Minimum width for layer 51 (M6) is 3.0 um
minwidth	\$	1.0		# Minimum width for all non M6 metal or poly layers is 1.0 um
minspace	\$	2.0		# Minimum space for all remaining layers is 2.0
gridsnap		0.01		# Snap all vertices to the nearest hundreth of a micron

ENDDRCRULES

ENDTECHNOLOGY

Spiral Value Proposition

Advantages Over Pre-Characterized Libraries

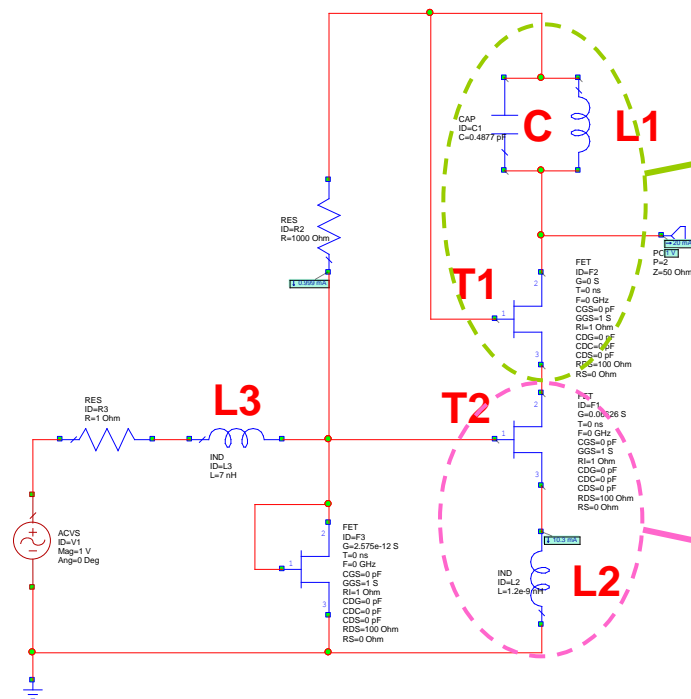
Pre-Characterized Libraries

1. Accurate
2. Only specific Inductors Allowed can dramatically limit design
3. Very significant design and measurement effort
4. Available after running test chips only
5. Extensive rework if process is changed

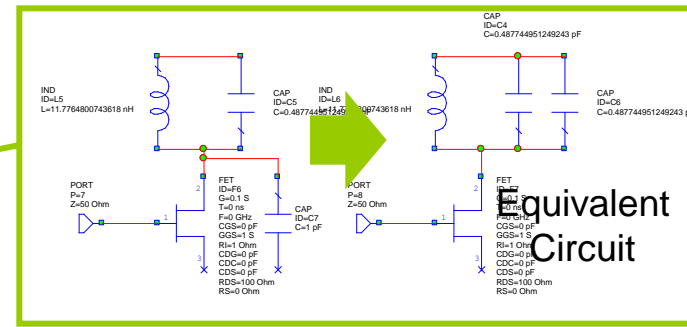
SPIRAL

1. Accurate
2. Inductors optimized for particular design
3. Minimum possible effort
4. Available immediately
5. Process changes easily incorporated

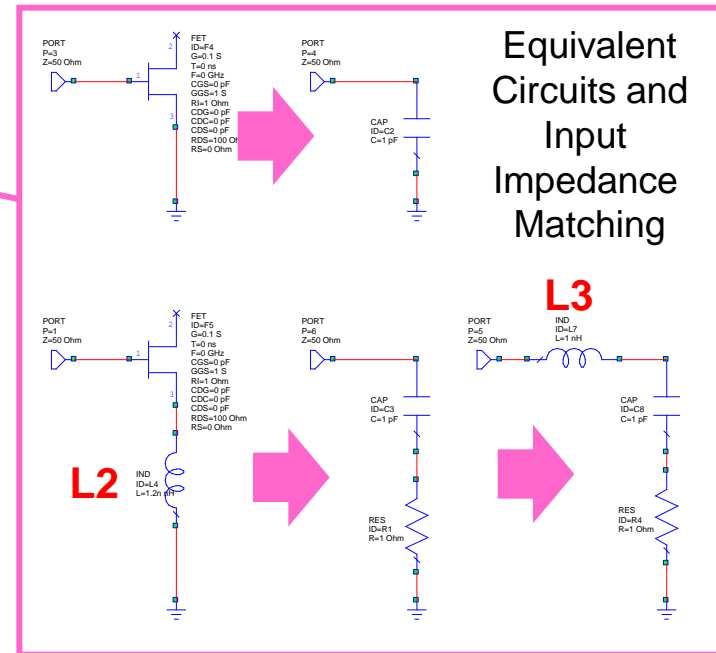
Why Optimized Spirals are Critical in an LNA



**L1, L2, L3, C, T1, and T2
Sizes are all related!**



**Equivalent
Circuit**



**Equivalent
Circuits and
Input
Impedance
Matching**

**Tuning cannot easily be achieved with a
predefined library of inductors**

Spiral Value Proposition

Advantages Over

Full Wave Solvers

Full Wave Solvers

1. Analysis tool
2. Electromagnetic expertise required
3. Extensive tool experience
4. Accurate (for experts) beyond resonance but difficulty at very low frequencies
5. Hours to generate input plus several hours to run analysis on a single inductor
6. Output is S-Parameters requires separate fitting step to get SPICE
7. Not integrated with design environments

SPIRAL

1. Synthesis Tool
2. No EM expertise required – easily used by RF designers
3. Minimum training required
4. Accurate up to resonance and very accurate low frequency results
5. Whole process runs in seconds or minutes including generation of fit models
6. Automated SPICE models both distributed and lumped available
7. Completely integrated with Cadence Composer & Artist

Spiral Value Proposition

Advantages Over

Analytical Tools

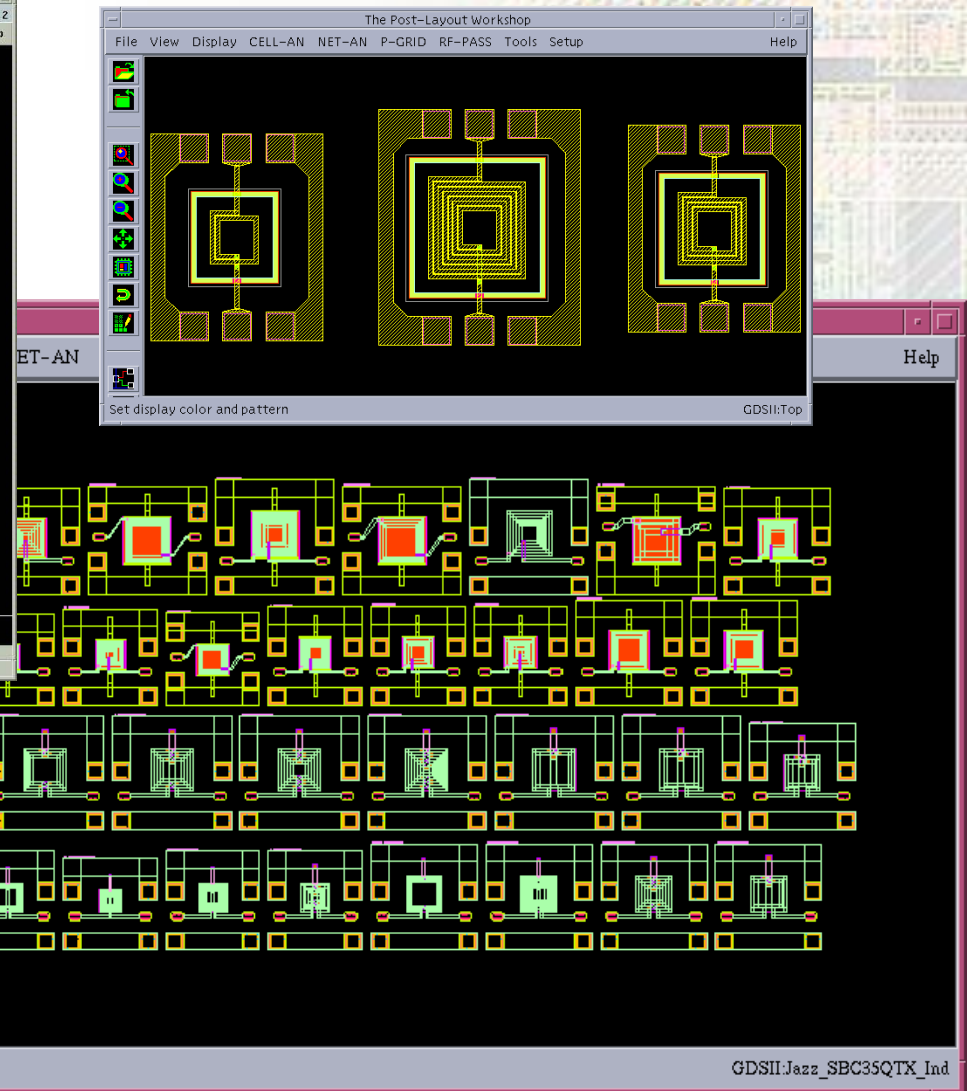
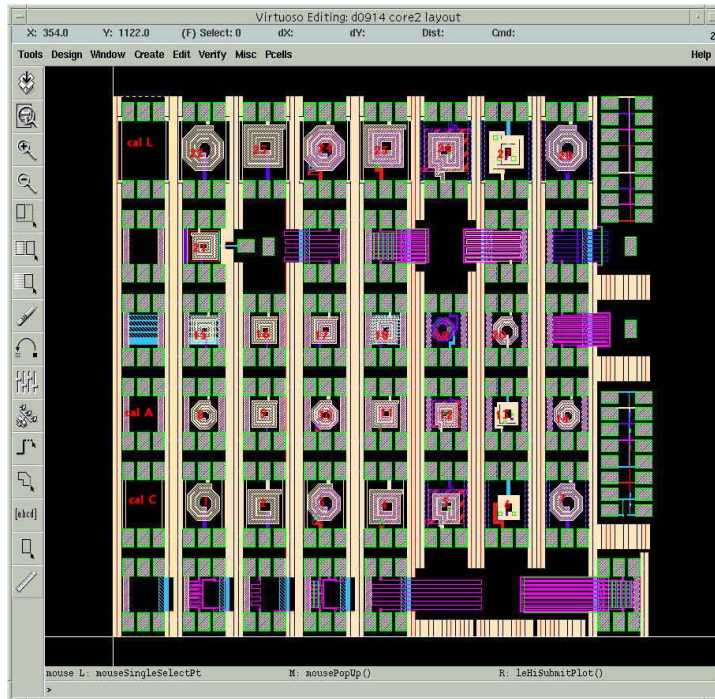
Analytical Tools

1. Analysis tool
2. Cheap – sometimes free
3. Difficult to use
4. Accurate DC results, extreme difficulty with RF results
5. Outputs are incomplete – does not include S, Y and Z parameters, plots of LRQ, layouts, etc...
6. Separate fitting step to get lumped SPICE models
7. Not integrated with design environments

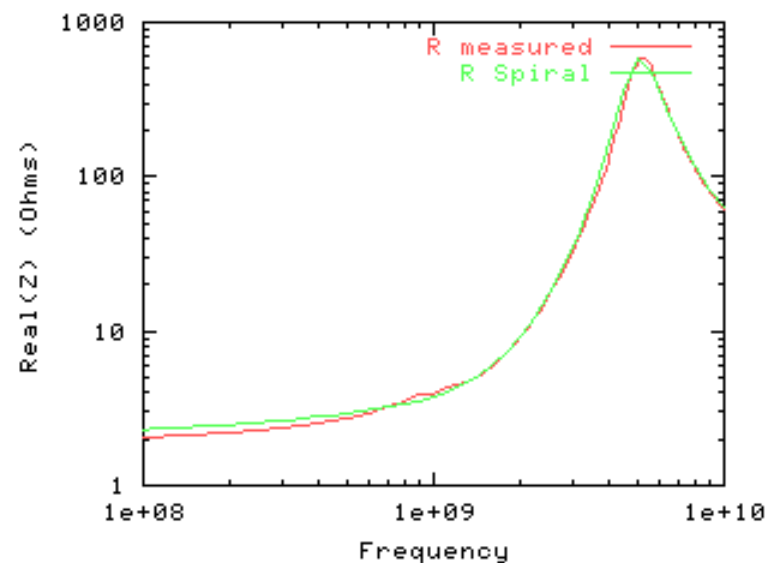
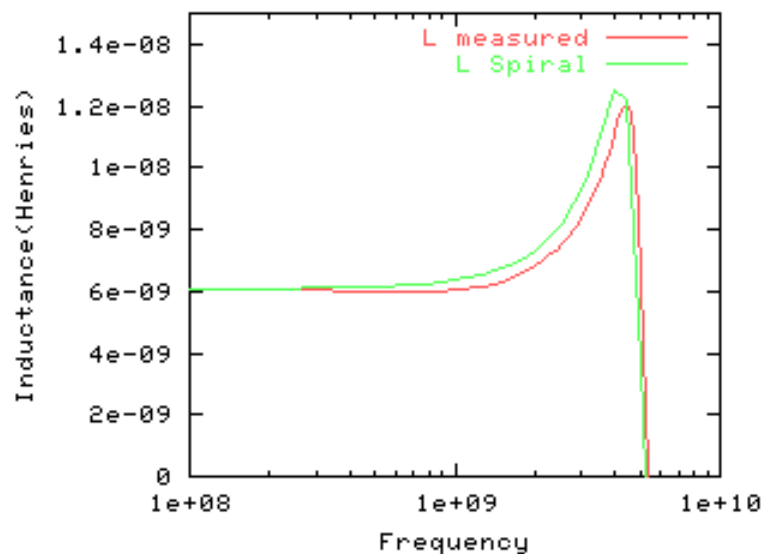
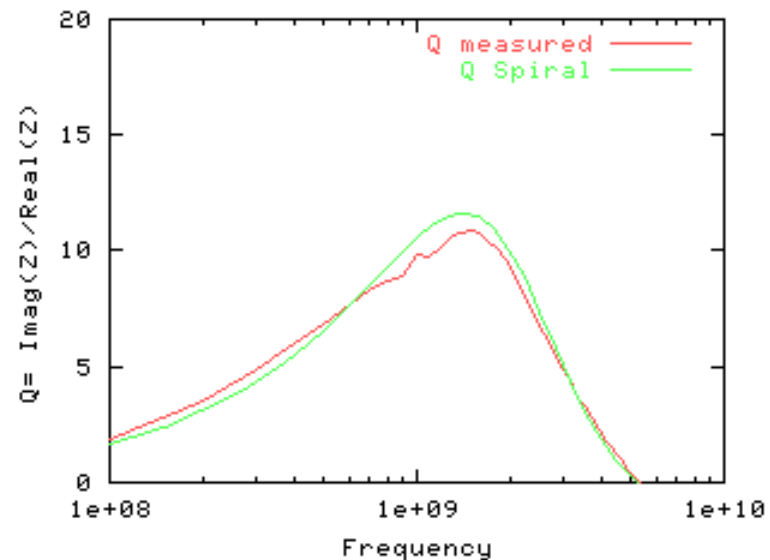
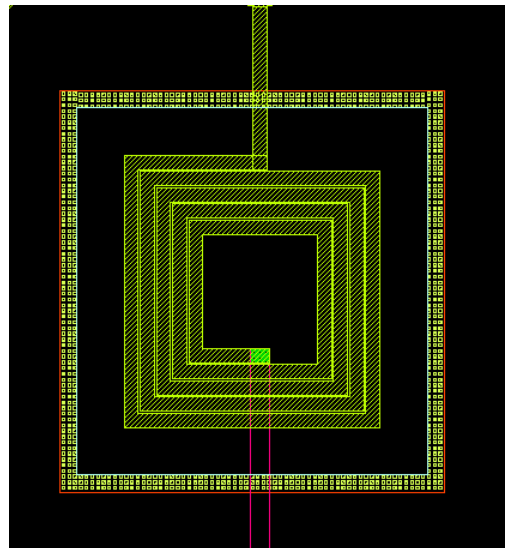
SPIRAL

1. Synthesis Tool
2. Commercial Product
3. Very easy to use
4. Accurate DC results & highly accurate up to resonance
5. Complete set of outputs including S, Y and Z parameters, LRQ, DRC correct layouts etc...
6. Automated SPICE models both distributed and lumped available
7. Completely integrated with Cadence Composer & Artist

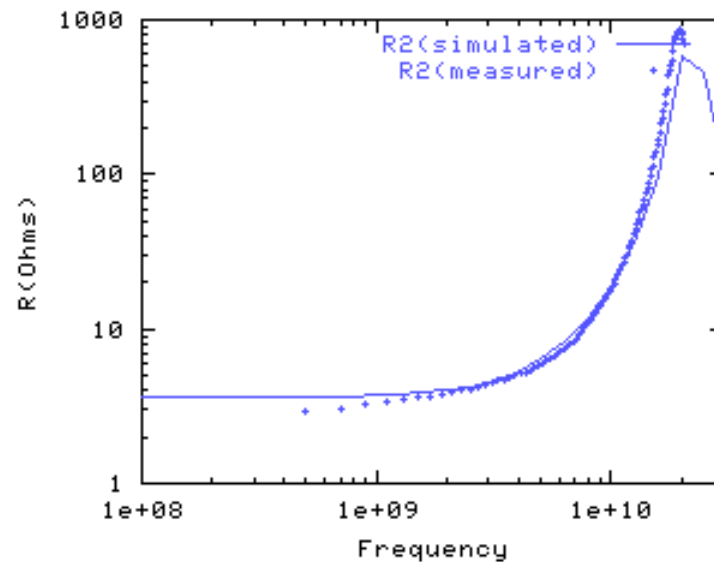
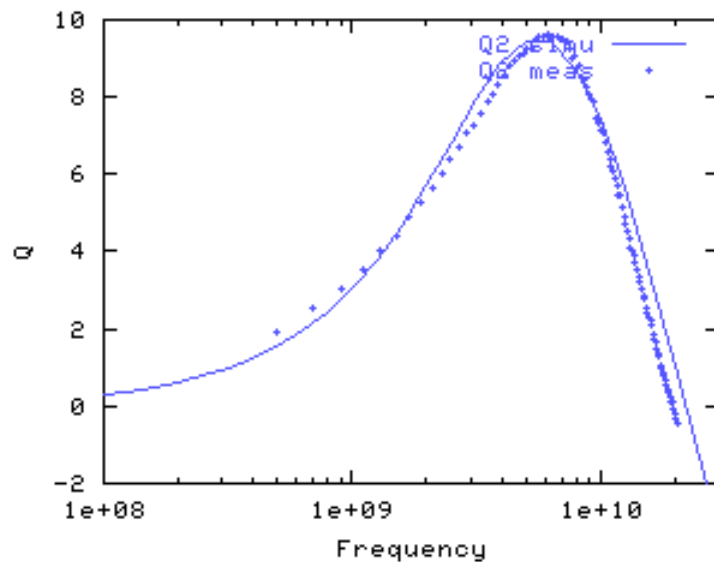
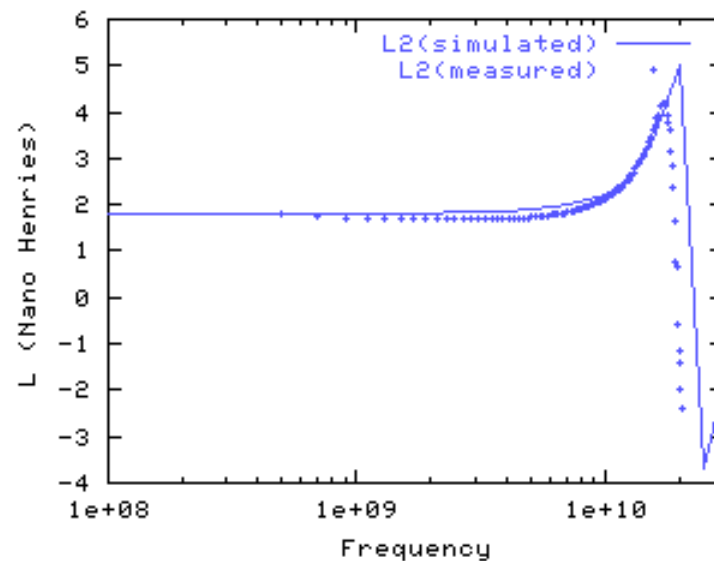
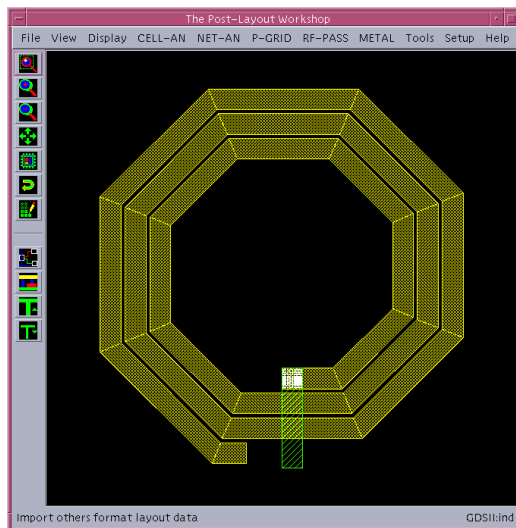
Spiral Extensively Validated Using With Customers and Test Chips



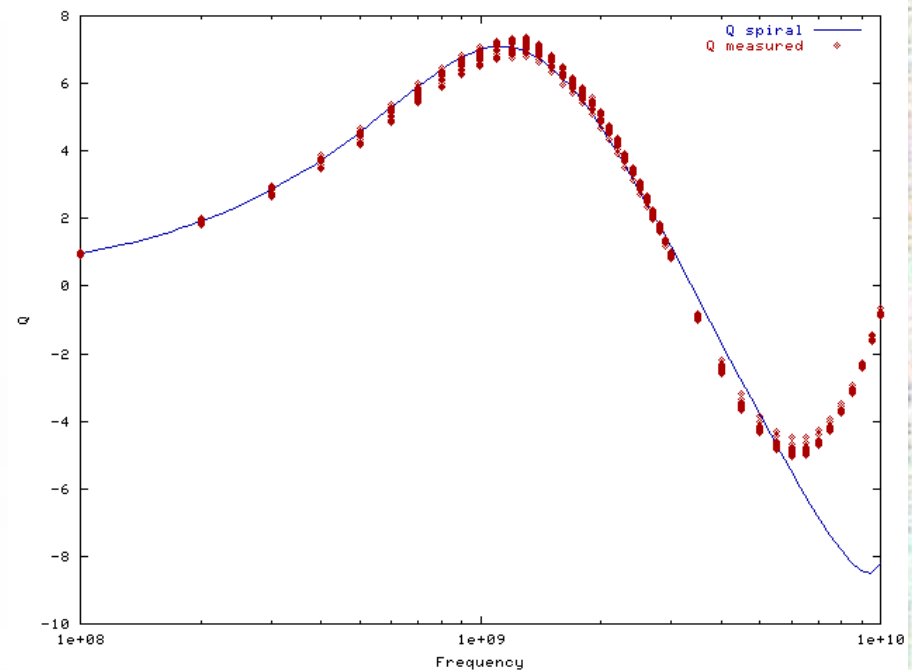
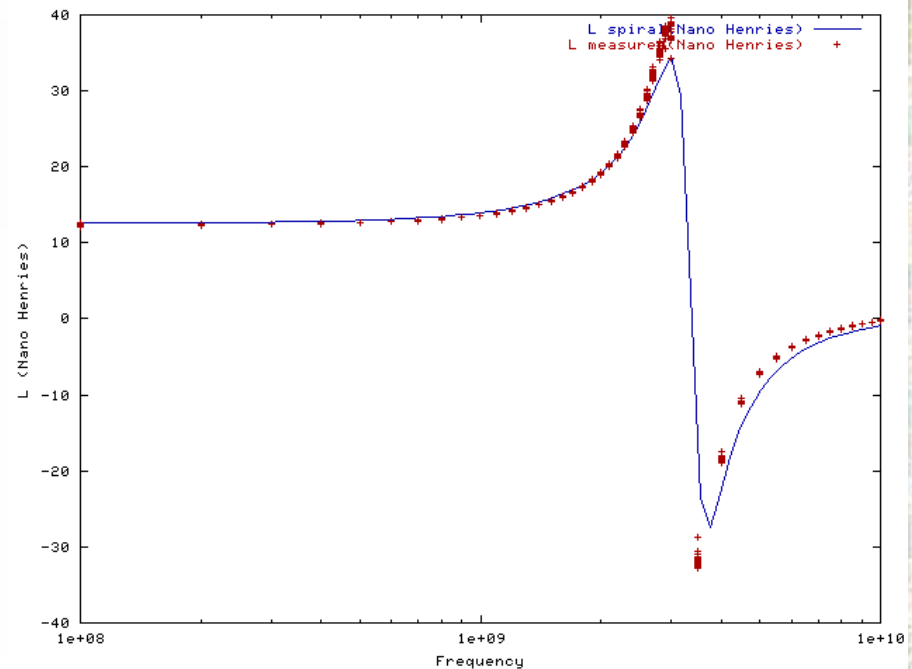
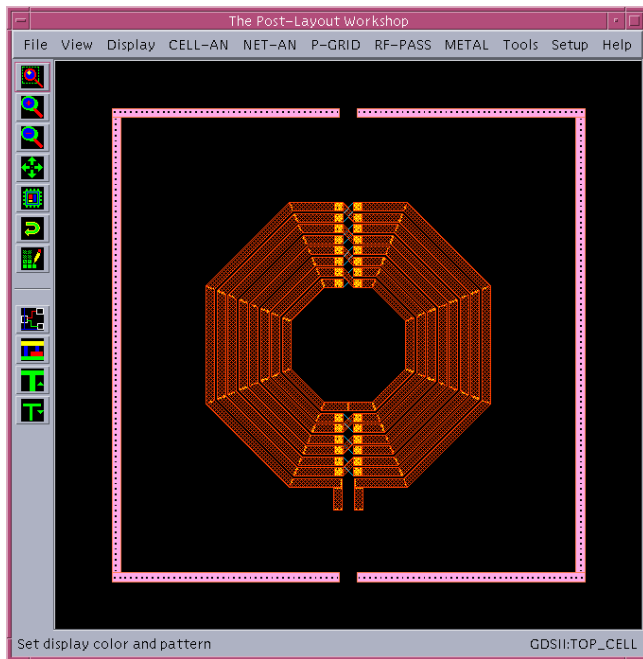
LRQ over Frequency Comparison Against Foundry Measurements (0.13 μm Process)



Asian Foundry: Measured Versus Simulated (0.18 um Process)



Measured versus simulated across multiple lots and wafers (0.18 μm Process)



Summary

- **Fully Automatic Inductor Synthesis**
 - Circuit Specific Inductor Optimization
 - Evaluates 1000's of Alternatives in Seconds
 - Easy to Use and Deploy
 - Library Development or Designer's Desktop
- **High Accuracy Models Match Silicon**
 - Improves Overall Design Performance
- **Ready for 90nm & 65nm Technologies**
 - Slotting and Dummy Metal Fill

Inductance Calculation in Spiral

Partial Inductance Approach

Six Self Inductances: $L_1, L_2, L_3, L_4, L_5, L_6$

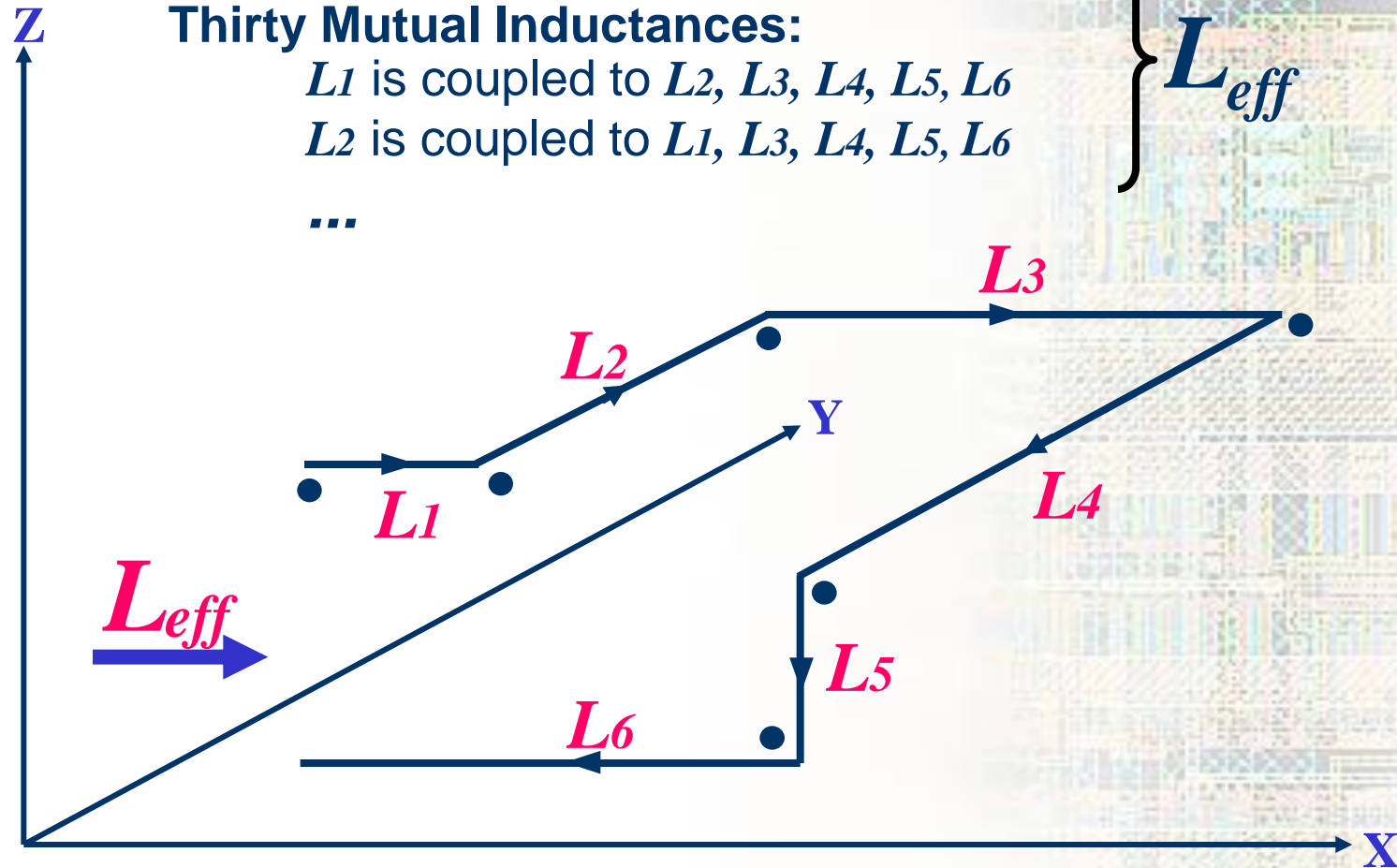
Thirty Mutual Inductances:

L_1 is coupled to L_2, L_3, L_4, L_5, L_6

L_2 is coupled to L_1, L_3, L_4, L_5, L_6

...

} L_{eff}



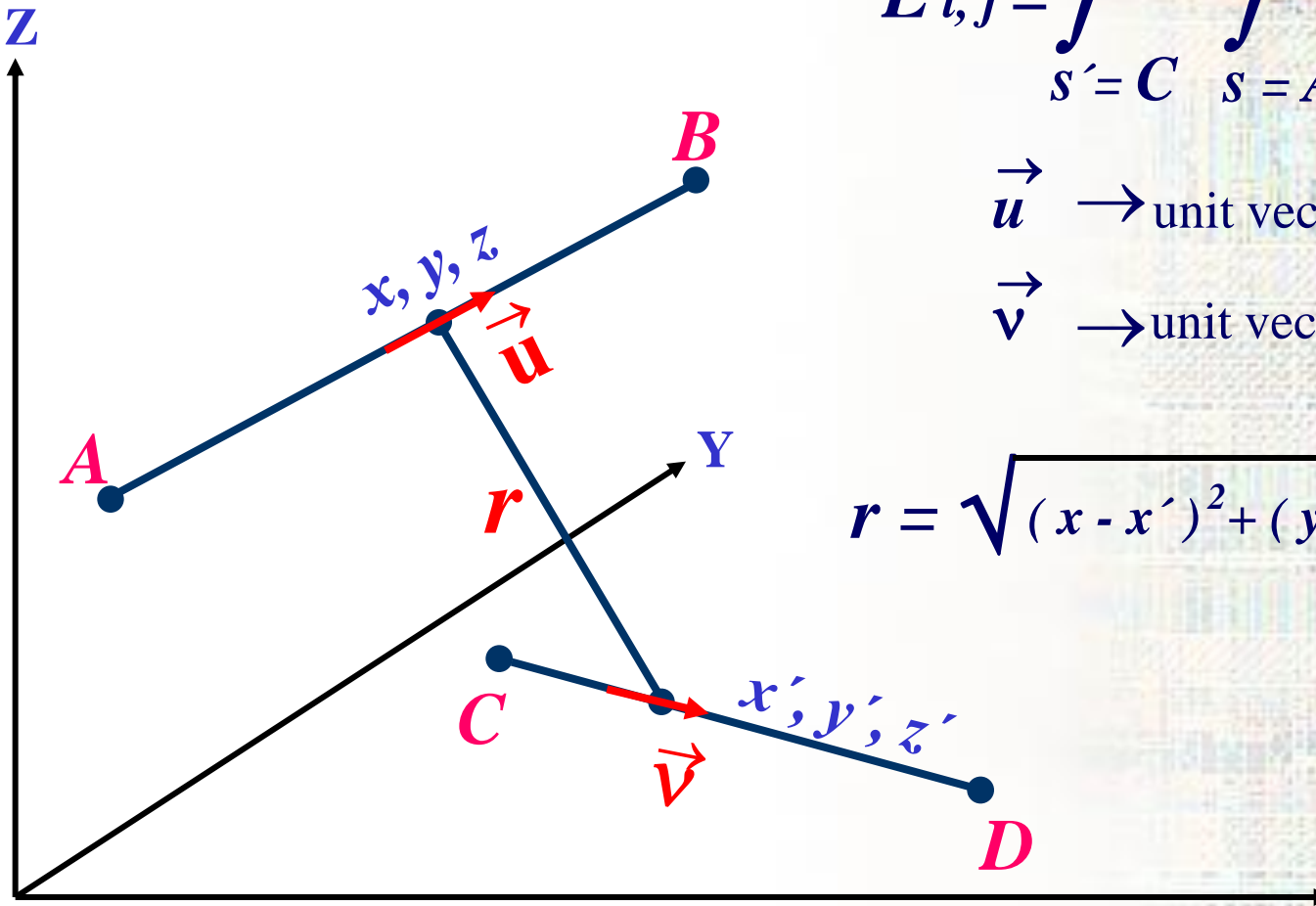
Neumann Formulation of Mutual Inductance

$$L_{i,j} = \int_{s'=C}^D \int_{s=A}^B \frac{\vec{u} \cdot \vec{v}}{r} ds ds'$$

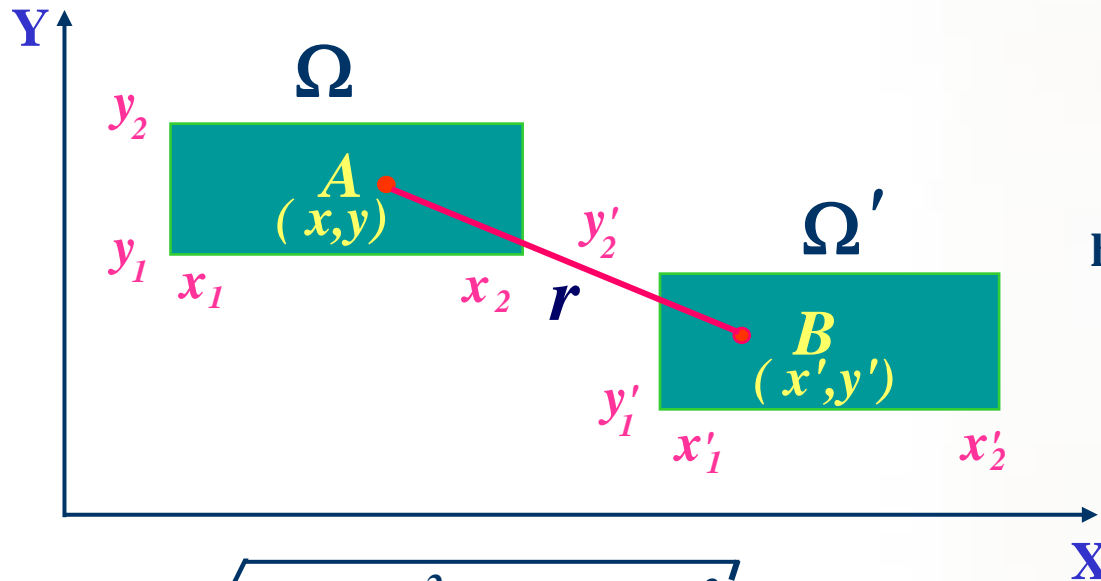
\vec{u} → unit vector along AB

\vec{v} → unit vector along CD

$$r = \sqrt{(x - x')^2 + (y - y')^2 + (z - z')^2}$$



Geometric Distance Between Objects

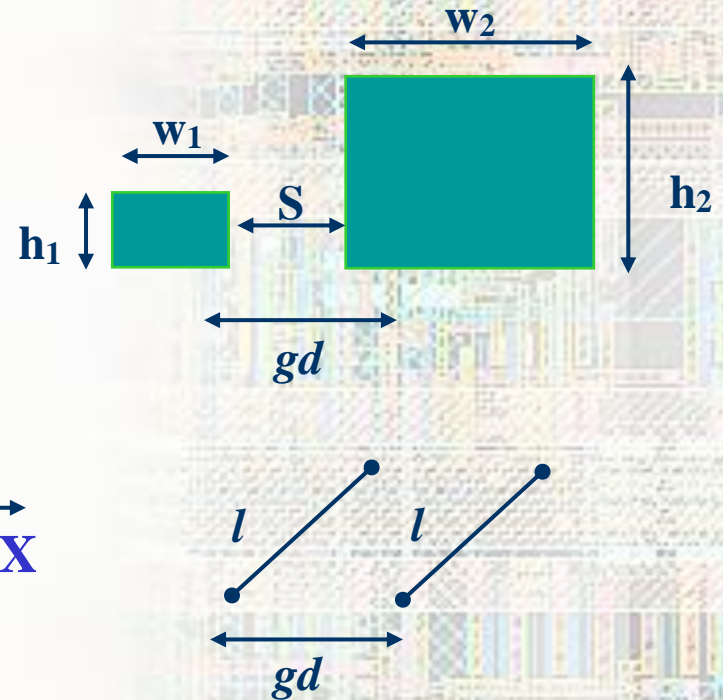


$$r = \sqrt{(x - x')^2 + (y - y')^2}$$

$$gd = \int_{\Omega} \int_{\Omega'} \ln(r) d\Omega d\Omega'$$

$$gd = \int_{y'=y_1'}^{y_2'} \int_{y=y_1}^{y_2} \int_{x'=x_1'}^{x_2'} \int_{x=x_1}^{x_2} \ln \sqrt{(x - x')^2 + (y - y')^2} dx dx' dy dy'$$

$$\ln \sqrt{(x - x')^2 + (y - y')^2} dx dx' dy dy'$$



Current Distribution Due to Skin and Proximity Effects

2.5 Turn Square Spiral
100 μm Inner Diameter
6.5 μm Width
4 μm Thickness
2.1 μm Spacing

